

Mini –Lab Plasma-Pod System

Plasma Pod RIE/Etch Plasma System

- **Small System Footprint**
- **Touch Screen Interface**
- **Aluminum Chamber**
- **External Gas Box**
- **RF Gen with Auto-Match**
- **Internal Turbo Pump**
- **125mm Electrode with Dark Space Shield**
- **RIE or Plasma Etching results**



The Plasma-Pod System is designed for R & D processes on small components and substrates up to 125mm in diameter.

The Plasma-Pod has an aluminum chamber with a temperature controlled substrate electrode accessible via the pneumatically operated top electrode. The system is equipped with a PLC control unit which interfaces with the operator touch screen. This control system allows manual or automatic operation, with process recipe storage and data logging.

Ethernet connection is also available for system monitoring. Systems can be configured to suit customer requirements and specific processes.



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